

Listing of Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Cancelled)
2. (Cancelled)
3. (Cancelled).
4. (Cancelled)
5. (Cancelled)
6. (Currently amended) The method according to claim 11 wherein the measuring occurs in the ~~at least one~~ first or second deposition chambers or both.
7. (Currently amended) The method according to claim 11 wherein the properties include ~~target~~ thickness of the organic layers and the adjusting step adjusts the deposition towards ~~such a~~ target thickness.
8. (Currently amended) The method according to claim 11 wherein the properties include dopant concentration, chemical composition, or optical properties or combinations thereof.
9. (Currently amended) The method according to claim 11 further including the step of moving the substrate from the ~~at least one~~ first or second deposition chamber into a measurement chamber where the property is measured.
10. (Cancelled)
11. (Currently amended) A method for making an OLED device having a plurality of organic layers, comprising:
 - a) providing a substrate having ~~one or more~~ a plurality of test regions and one or more device regions wherein the ~~one or more~~ plurality of test regions are spaced apart from the one or more device region;
 - b) moving the substrate sequentially into ~~a least two~~ first and second deposition chambers for respectively depositing first and second different organic layers of the OLED device ~~deposition of at least one organic layer in each deposition chamber~~;
 - c) depositing the ~~at least one~~ first organic layer in the first deposition chamber onto a device region through a first opening in a first shadowmask and onto a first test region through a second opening in the first

shadowmask and depositing the second organic layer onto the device region through a first opening in a second shadowmask and onto a second test region through a second opening in the second shadowmask wherein the first test region is spaced apart from the second test region ~~each chamber through at least one opening in a shadowmask selected for each deposition chamber onto the one or more device regions and onto one or more test regions on the substrate;~~

d) measuring a property of ~~the at least one~~ each organic layer in the ~~at least one~~ first and second test regions; and

e) adjusting the deposition process of either the first or second organic layer or both in accordance with the measured property.

12. (Cancelled).

13. (Currently amended) The method according to claim 11 wherein measurement of the properties ~~for each test in the first and second test regions~~ is done after ~~all~~ the organic layers of the first and second test regions are deposited or after each organic layer of each test region is deposited.

14. (Original) The method according to claim 11 where the substrate is kept at a reduced vacuum pressure during deposition and measurement.

15. (Original) The method according to claim 14 where the pressure of the vacuum is less than 0.1 Pa.

16. (Original) The method according to claim 14 where the pressure of the vacuum is less than 0.001 Pa.

17. (Currently amended) The method according to claim 11 wherein the first and second shadowmasks each include a plurality of openings corresponding to a plurality of different device regions further including:

~~_____ i) _____ providing a shadowmask structure for each chamber having a plurality of openings which respectively correspond to different device regions and arranged to permit the deposition of organic material on the substrate of such devices; and~~

~~_____ ii) _____ forming at least one test opening spaced from the plurality of openings for permitting the deposition of organic material onto a test region of the substrate.~~

18. (Cancelled)